

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 230420US41YA		SERIAL NO. 10/673,583	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Andrej S. MITROVIC			
				FILING DATE September 30, 2003		GROUP 2128	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	US 6,529,789	3/2003	Campbell, et al.			
	AB	US 6,618,856	9/2003	Coburn, et al.			
	AC	US 2005-0071037	3/31/2005	Strang			
	AD	US 2005-0071035	3/31/2005	Strang			
	AE	US 2005-0071038	3/31/2005	Strang			
	AF	US 2005-0071036	3/31/2005	Mitrovic			
	AG	US 2005-0071039	3/31/2005	Mitrovic			
	AH	US 6,198,980 B1	3/2001	Costanza, John R.			
	AI	US 7,107,571 B2	9/2006	Chang, et al.			
	AJ	US 5,741,070	4/21/1998	Mehrdad Mahmud Moslehi			
	AK	US 2004/0058255 A1	3/25/2004	Scott Jensen, et al			
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AO	CN 1335558A	2/13/2002	China (with Partial English Translation)	X		
	AP	WO 02/07210 A2	1/24/2002	WIPO			X
	AQ	EP 0 718 595 A2	6/26/1996	EUROPE			X
	AR	JP 2004-527117	9/2/2004	Japan (Corresponding Abstract from WO/02077589)			X
	AS	WO 03/060779 A1	7/24/2003	WIPO			X
	AT	JP 2005-515623	5/26/2005	JAPAN (With English Abstract)			X
	AU	WO 03/009345 A2	1/30/2003	WIPO			X
	AV	JP 2005-522018	7/21/2005	JAPAN (With English Abstract)			X
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW	Agam SHAH, "TILERA TARGETS INTEL, AMD WITH 100-CORE PROCESSOR", PCWorld Solved, IDG News October 26, 2009, pages 1-3					
	AX	Office Action issued March 30, 2011 in Japanese Patent Application No. 10-2006-7006632, (with English-language Translation) pages 1-17					
	AY	Su-shing CHEN, "AEMPES: An expert system for in-situ diagnostics and process monitoring", Semiconductor Manufacturing Science Symposium, 1990, IEEE/SEMI International, 21-23 May 1990, pages 119-122					
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner					Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 230420US41YA		SERIAL NO. 10/673,583	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Andrej S. MITROVIC			
				FILING DATE September 30, 2003		GROUP 2128	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AAA	US 2003/0003607	1/2/2003	Kagoshima et al			
	AAB	US 6,185,472	2/6/2001	Onga, et al.			
	AAC	US 7,047,095 B2	5/16/2006	Tomoyasu			
	AAD	US 6,587,744 B1	7/1/2003	Stoddard, et al.			
	AAE						
	AAF						
	AAG						
	AAH						
	AAI						
	AAJ						
	AAK						
	AAL						
	AAM						
	AAN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AAO	JP 2003-17471	1/17/2003	JAPAN (With English Abstract)			X
	AAP	WO 02/065511 A2	8/22/2002	WIPO			X
	AAQ	JP 2004-524685	8/12/2004	JAPAN			X
	AAR	WO 02/069063 A2	9/6/2002	WIPO			X
	AAS	JP 2004-531878	10/14/2004	JAPAN			X
	AAT	JP 2000-517473	12/26/2000	JAPAN (With English Abstract)			X
	AAU	WO 03/058699 A1	7/17/2003	WIPO			X
	AAV	JP 2005-514790	5/19/2005	JAPAN (With English Abstract)			X
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AAW	Naomi YONEMURA, et al., "HEAT ANALYSIS ON INSULATED METAL SUBSTRATES", Proc. Of the 1994 IMC, 100 (1994) pages 1407-1410					
	AAX	Office Action issued February 22, 2011 in Japanese Patent Application No. 2006-533881 (English-language) pages 1-9					
	AAZ	Office Action issued September 7, 2007 in People's Republic of China Patent Application No. 2004 80028518.0 (with English-language translation) pages 1-62					
	AAZ	Office Action issued December 28, 2007 in People's Republic of China Patent Application No. 200480028479.4 (with English-language translation) pages 1-30				<input type="checkbox"/> Additional References sheet(s) attached	
Examiner					Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 230420US41YA		SERIAL NO. 10/673,583	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Andrej S. MITROVIC			
				FILING DATE September 30, 2003		GROUP 2128	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AAAA						
	AAAB						
	AAAC						
	AAAD						
	AAAE						
	AAAF						
	AAAG						
	AAAH						
	AAAI						
	AAAJ						
	AAAK						
	AAAL						
	AAAM						
	AAAN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AAAO	JP 2002-367875	12/20/2002	JAPAN (With English Abstract)			X
	AAAP	JP 2003-502771	1/21/2003	JAPAN (With English Abstract)			X
	AAAQ	WO 02/077589 A2	10/3/2002	WIPO			X
	AAAR	KR 1999-071784	4/2/1999	Korea (with corresponding to US. Patent Application No. 5,719,796 attached as a courtesy herewith)	X		
	AAAS	JP 11-330449	11/30/1999	JAPAN (with English Abstract)			X
	AAAT	JP 2000-269105	9/29/2000	JAPAN (with English Abstract)			X
	AAAU	JP 081484400 A	6/7/1996	JAPAN (with English Abstract)			X
	AAAV	JP 2000-517473	12/26/2000	JAPAN (with English Abstract from Corresponding Case)			X
	AAAW	JP 11-176906	7/2/1999	JAPAN (with English Abstract)			X
	AAAX						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AAAY	Office Action issued June 19, 2009 in The People's Republic of China Patent Application No. 200480028517.6 (with English-language translation) pages 1-38					
	AAAZ	Heru SETYAWAN, et al. "VISULIZATION AND NUMERICAL SIMULATION OF FINE PARTICLE TRANSPORT IN A LOW-PRESSURE PARALLEL PLATE CHEMICAL VAPOR DEPOSITION ", Chemical Engineering Science 57 (2002) pages 497-506					
							<input type="checkbox"/> Additional References sheet(s) attached
Examiner					Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							